# Compound Semiconductor Materials Japan TC Chapter

# Meeting Summary and Minutes

Japan Winter Meetings 2024

Tuesday, December 12, 2024 13:00 – 15:00 JST

OVTCCM/ SEMI Japan Office, Tokyo, Japan (Hybrid), SEMICON Japan 2024

**TC Chapter Announcements**

*Next TC Chapter Meeting*

Friday, May 23, 2024, 13:00-16:00 JST

OVTCCM/ SEMI Japan Office, Tokyo, Japan (Hybrid)

**Table 1 Meeting Attendees**

*Italics* indicate virtual participants

**Co-Chairs:** Masayoshi Obara (Shin-Etsu Handotai)
**SEMI Staff:** Hirofumi Kanno

| *Company* | *Last* | *First* | *Company* | *Last* | *First* |
|---|---|---|---|---|---|
| *DENSO* | *Aoki* | *Yutaka* | *Self* | *Kitabatake* | *Makoto* |
| *SiC Alliance* | *Toda* | *Keiji* | Shin-Etsu Handotai | Obara | Masayoshi |
| *Resonac* | *Matsuse* | *Akihiro* | *AIST-National Institute of Advanced Industrial Science and Technology* | *Senzaki* | *Junji* |
| *Mitsubishi Electric* | *Iwamatsu* | *Toshiaki* | SEMI Japan | Kanno | Hirofumi |

**Table 2 Leadership Changes**

| *WG/TF/SC/TC Name* | *Previous Leader* | *New Leader* |
|---|---|---|
| None | | |

**Table 3 TC Chapter Structure Changes**

| *Previous WG/TF/SC Name* | *New WG/TF/SC Name or Status Change* |
|---|---|
| None | |

**Table 4 Ballot Results**

| *Document #* | *Document Title* | *Committee Action* |
|---|---|---|
| None | | |

### Table 5 Ratification Ballot Results

| *Document #* | *Document Title* | *ISC A&R Action* | *A&R Forms* |
|---|---|---|---|
| None | | | |

### Table 6 Activities Approved by the GCS between meetings of the TC Chapter

| *#* | *Type* | *SC/TF/WG* | *Details* |
|---|---|---|---|
| None | | | |

### Table 7 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

| *#* | *Type* | *SC/TF/WG* | *Details* |
|---|---|---|---|
| None | | | |

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:
http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF

### Table 8 Authorized Ballots

| *#* | *When* | *TF* | *Details* |
|---|---|---|---|
| 7211A | Cycle 3, 2025 | SiC Epitaxial Wafer liaison TF | Line-Item Revision to SEMI M92-0423, Specification for 4H-SiC Homoepitaxial Wafer |

### Table 9 SNARF(s) Granted a One-Year Extension

| *#* | *TF* | *Title* | *Expiration Date* |
|---|---|---|---|
| None | | | |

### Table 10 SNARF(s) Cancelled

| *#* | *TF* | *Title* |
|---|---|---|
| None | | |

### Table 11 Standard(s) to receive Inactive Status

| *Standard Designation* | *Title* |
|---|---|
| None | |

### Table 12 New Action Items

| *Item #* | *Assigned to* | *Details* |
|---|---|---|
| None | | |

### Table 13 Previous Meeting Action Items

| *Item #* | *Assigned to* | *Details* |
|---|---|---|
| 20220119-03 | Silicon Carbide Substrate Liaison | To confirm the contents of Document #6693, 6767-9 and their ballot schedule and share them to the JA TF members and hold meetings as necessary. →Open |

**Table 13 Previous Meeting Action Items**

| *Item #* | *Assigned to* | *Details* |
|---|---|---|
| | TF leaders and SiC Epitaxial Wafer liaison TF leaders | |
| CSM_20240521-01 | SEMI Staff | To send Doc.#7211 Line Item 3-5 adjudication results to the ISC A&R SC for procedural review. →Open |
| CSM_20240521-02 | CSM_20240521-01 | To have an explanatory session for Connect@SEMI. →Open |

## 1 Welcome, Reminders, and Introductions

Masayoshi Obara (Shin-Etsu Handotai) called the meeting to order at 13:00. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

**Attachment**: 01_Required Meeting Elements March 2024_J

## 2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

| | |
|---|---|
| **Motion:** | Approve the minutes with some change. |
| **By / 2nd:** | Kitabatake Makoto (Self)/ Kenji Toda (SiC Alliance) |
| **Discussion:** | Toda-san's correct full name is Kenji (Not Keiji) Toda. |
| **Vote:** | 6-Y 0-N. Motion passed. |

**Attachment**: 02_CSM JA TC Minutes_20240521_R1HK FIXED

## 3 Liaison Reports

### 3.1 *Japan Regional Standards Committee (JRSC)*

Hirofumi Kanno (SEMI Japan) reported for the JRSC. At the previous meeting held on December 9. SEMI Japan staff announced that Global Standards Summit is held at December 12.

### 3.2 *Global Coordinating Subcommittee (GCS)*

None

### 3.3 *Compound Semiconductor Materials Europe TC Chapter*

Hirofumi Kanno (SEMI Japan) reported for the Compound Semiconductor Materials Europe TC Chapter. Of note:

- Newly appointed chair at SEMICON Europa 2024 - Christian Kranert (Fraunhofer IISB)

**Attachment**: 3_EU CSM Liaison Report November 2024

### 3.4 *Compound Semiconductor Materials North America TC Chapter*

Hirofumi Kanno (SEMI Japan) reported for the Compound Semiconductor Materials North America TC Chapter that there had been no updates from the previous meeting.

### 3.5 *Compound Semiconductor Materials China TC Chapter*

Hirofumi Kanno (SEMI Japan) reported for the Compound Semiconductor Materials China TC Chapter. Of note:

**Attachment:** 4_CSM China TC Chapter Liaison Report Dec 2024

## 4 SEMI Staff Report

Hirofumi Kanno (SEMI Japan) gave the SEMI Staff Report. Of note:

- SEMI Global2024 & 2025 Calendar of Events
- Global Standards Summit 2024
- SEMI Standards Friendship Party &Award Ceremony
- Regulations & Procedure Manual Updates

**Attachment:** 5_Staff Report November 2024 v4_ay

## 5 Ballot Review

None

## 6 Subcommittee and Task Force Reports

### 6.1 *Silicon Carbide Substrate Liaison Task Force*

Masayoshi Obara (Shin-Etsu Handotai) reported no update on this Task Force.

### 6.2 *SiC Epitaxial Wafer Liaison Task Force*

Masayoshi Obara (Shin-Etsu Handotai) plans to have the Task Force meeting. The topic will be the Line Item #1 and 2 on Document 7211A.

Motion: Authorize the Document 7211A (Line Item 1 & 2) Line-Item Revision to SEMI M92-0423, Specification for 4H-SiC Homoepitaxial Wafer issuance in Cycle 3, 2025 for Letter Ballot
By: Keiji Toda / SiC Alliance
Second: Makoto Kitabatake / Self
Discussion: None
Result: Result: 4-Y 0-N Voting Result: Pass - 100.00%. Voting Rule: Majority

## 7 Old Business

### 7.1 *Project Period Review*

None.

### 7.2 *5-Year Review*

None.

## 8 New Business

None

## 9 Next Meeting and Adjournment

The next meeting is scheduled for Friday, May 23rd, 2024, 13:00-16:00 JST, OVTCCM/ SEMI Japan Office, Tokyo, Japan (Hybrid). See http://www.semi.org/standards-events for the current list of events.

Adjournment: 15:00.

Respectfully submitted by:

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Email: hkanno@semi.org

Minutes tentatively approved by:

| | |
|---|---|
| Masayoshi Obara (Shin-Etsu Handotai), Co-chair | |

**Table 14 Index of Available Attachments**[#1]

| *Title* | *Title* |
|---|---|
| 01_Required Meeting Elements March 2024_J | 04_CSM China TC Chapter Liaison Report Dec 2024 |
| 02_CSM JA TC Minutes_20240521_R1HK FIXED | 05_Staff Report November 2024 v4_ay |
| 03_EU CSM Liaison Report November 2024 | |

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Akiko Yoshida at the contact information above.